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Misaizu et al.

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(54) **STRAIN GAUGE**

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(52) **U.S. Cl.**
USPC **D10/102; D10/83**

(58) **Field of Classification Search**
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CPC B60K 2001/003; B60K 5/04; G01P 1/02; G01P 1/07; G01P 1/12; G01P 3/02; G01P 3/26; G01P 3/64; G01P 9/00; G01D 1/04; G01L 1/04; G01L 1/08; G01L 1/10; G01L 1/12; G01L 1/14; G01L 3/00; G01L 7/00; G01L 1/2287; G01L 1/16; B23B 1/00; B23B 5/00; G01B 7/16; G01N 27/223; G01M 5/0091; B32B 27/281; B32B 15/43

See application file for complete search history.

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(57) **CLAIM**

The ornamental design for a strain gauge, as shown and described.

DESCRIPTION

FIG. 1 is a top plan view of a strain gauge, showing our new design;

FIG. 2 is a front view thereof;

FIG. 3 is a rear view thereof;

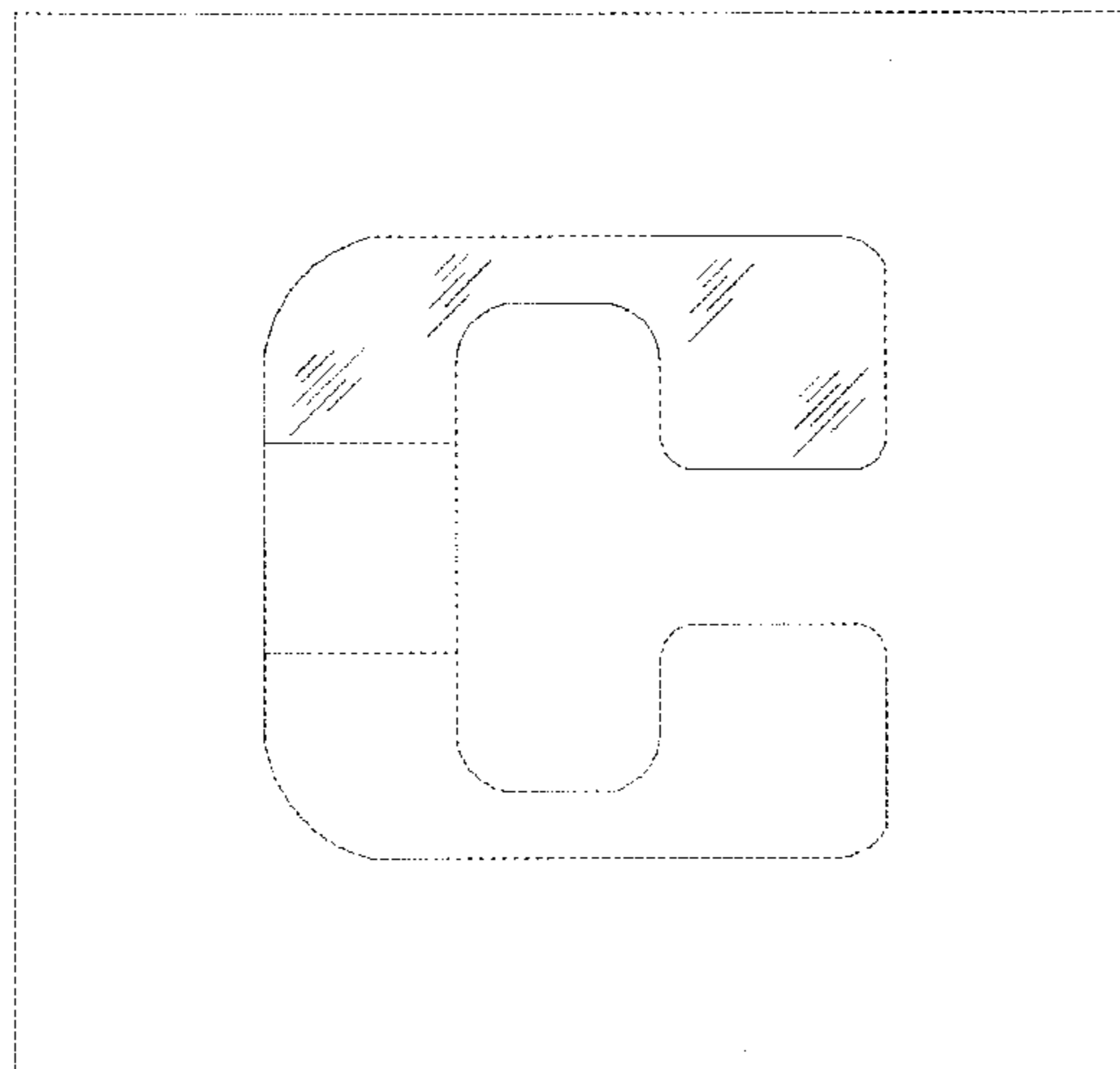
FIG. 4 is a right side view thereof;

FIG. 5 is a left side view thereof; and,

FIG. 6 is a bottom plan view thereof.

The broken lines shown in the drawings represent portions of the strain gauge that form no part of the claimed design.

1 Claim, 3 Drawing Sheets



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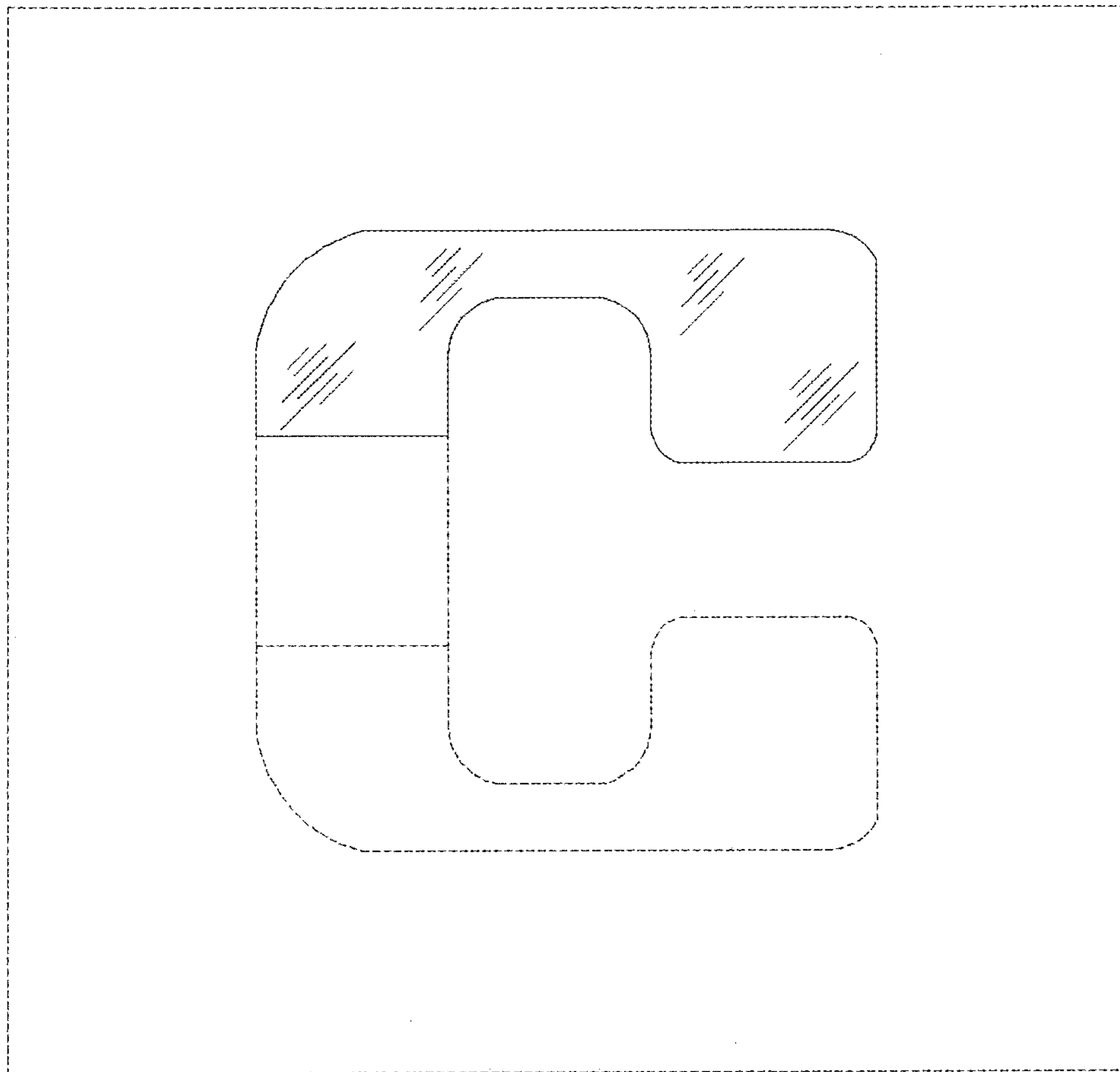


Fig. 1

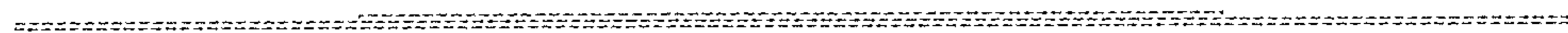


Fig. 2

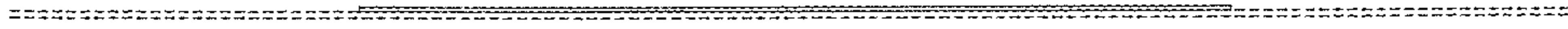


Fig. 3

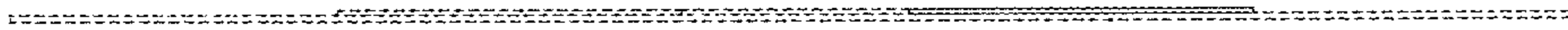


Fig. 4

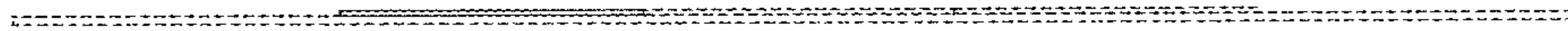


Fig. 5

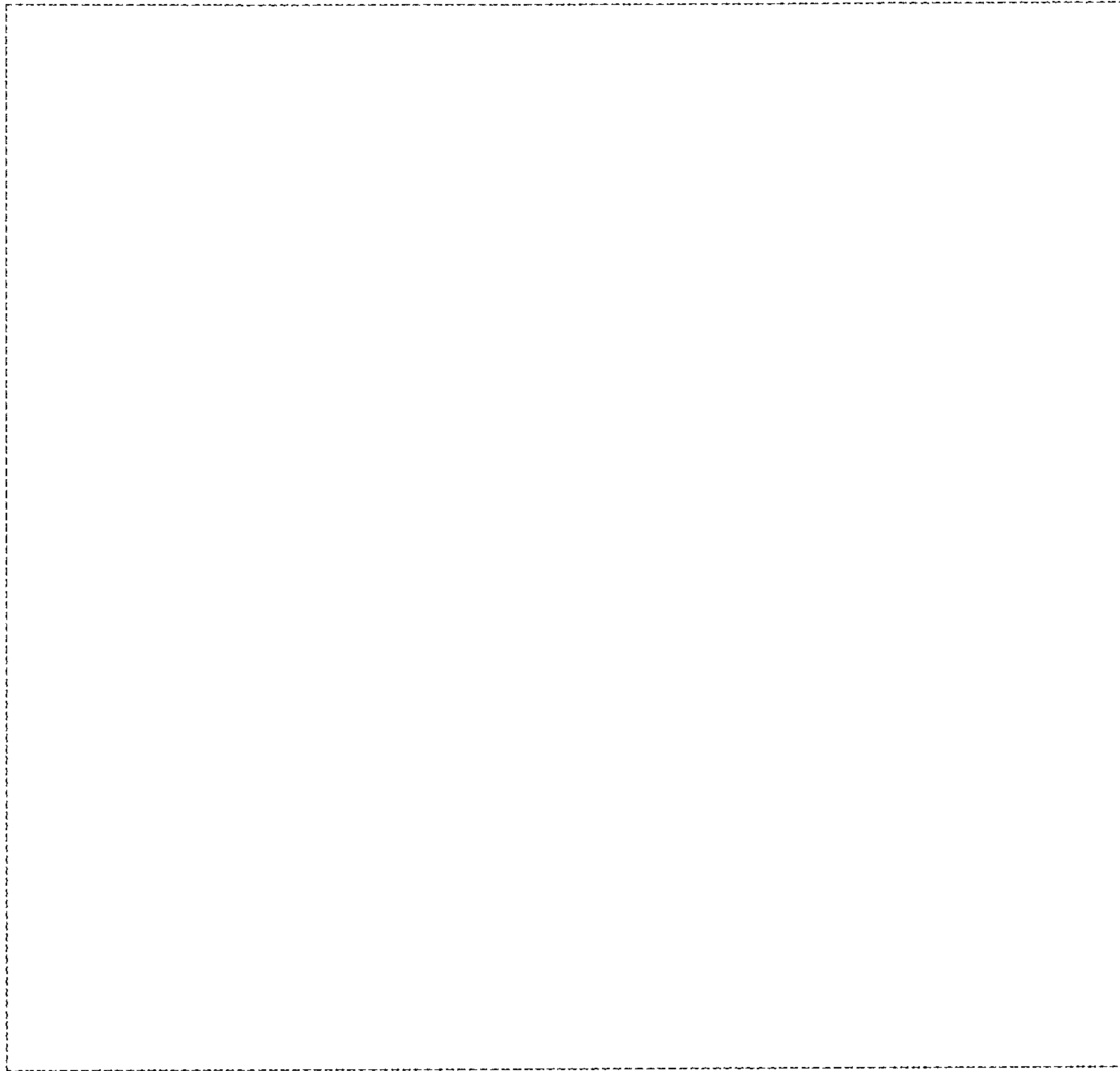


Fig. 6